## Abstract Submitted for the MAR06 Meeting of The American Physical Society

Spatial and pulse shape dependence of  $K\alpha$  source from high contrast fs laser plasmas in regime of Relativistic Engineering LIMING CHEN, Advanced Photon Research Center, Japan Atomic Energy Agency — Interaction of intense Ti: Sapphire laser with Cu foil targets has been studied by measuring hard X-ray generation. Hard x-ray spectroscopy and K $\alpha$  X-ray conversion efficiency ( $\eta_K$ ) from Cu plasma have been studied as a function of laser intensity via pulse duration scan (60 fs ~ 600 fs), laser pulse energy scan (60 mJ ~ 600 mJ) and target displacement scan from best focus. For intensity  $I > 1x10^{17} W/cm^2$ , the Cu  $\eta_K$  keep on increasing to reach a maximum value of  $1x10^{-4}$  at an intensity  $I = 1x10^{18} W/cm^2$ . The focusing was varied widely to give a range of intensities from  $10^{15}~W/cm^2 \sim$  $10^{18} W/cm^2$ . Two individual emission peaks are obtained, one is at best focal spot and the other is at larger target offset corresponding to  $\sim 10^{15} W/cm^2$ . Each peak is corresponding to different energy absorption mechanism. In addition, when we introduce slightly detuning of compressor gratings at the best focal condition, it shows  $\eta_K$  generated by negatively skewed 100 fs pulse width laser irradiation reach  $5x10^{-4}$  and almost 7 times greater than the case of positively skewed pulse. Vacuum Heating is greatly stimulated in this case and preciously control of pre-plasma is the key factor in tuning control of X-ray emission in relativistic fs regime.

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